



LEIBNIZ-Konferenz

Industrielle Revolution 4.0 im historischen Kontext

Jörg Ludewig

„Speicherchip-Packaging – die Technologi Lokomotive für das Back-end“

Dresden, 19. März 2015

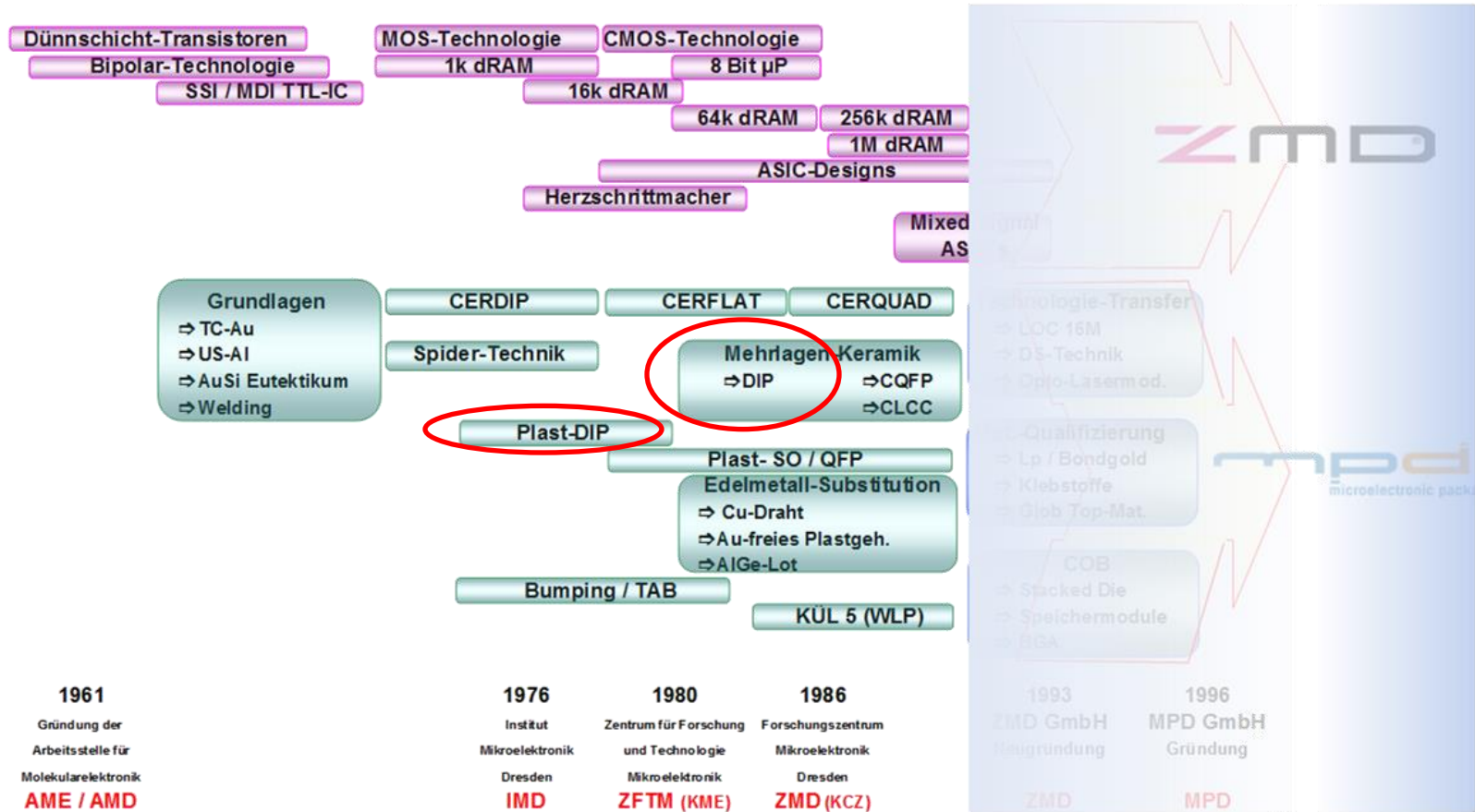


19. Leibnizkonferenz

- Anforderungen an Gehäuse 1 M Speicher
 - Bauform DIP 18
 - Reihenabstand 7,5 mm
 - Plast
 - Keramik
 - Standard-Montagetechnologie mit ggf. Chip-Schutz

1 M Speicher

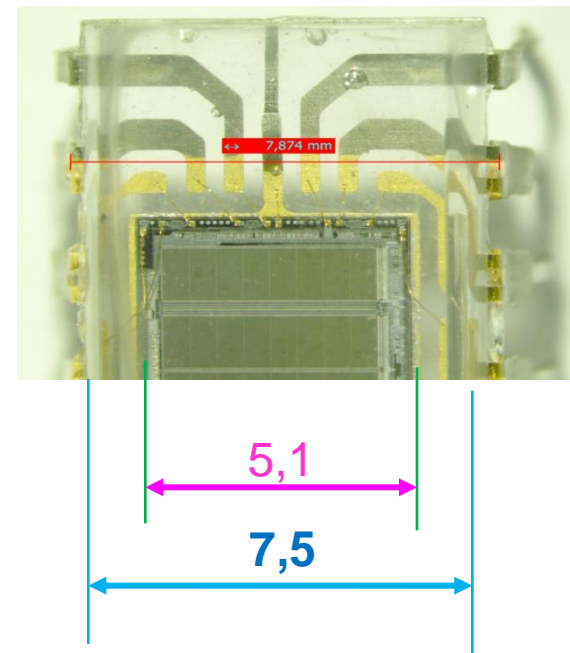
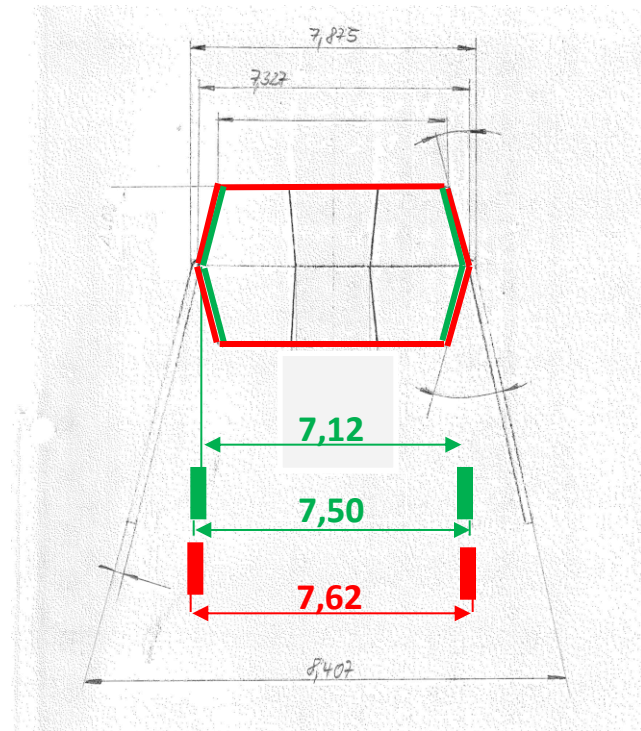
□ Entwicklung in Dresden



1 M Speicher

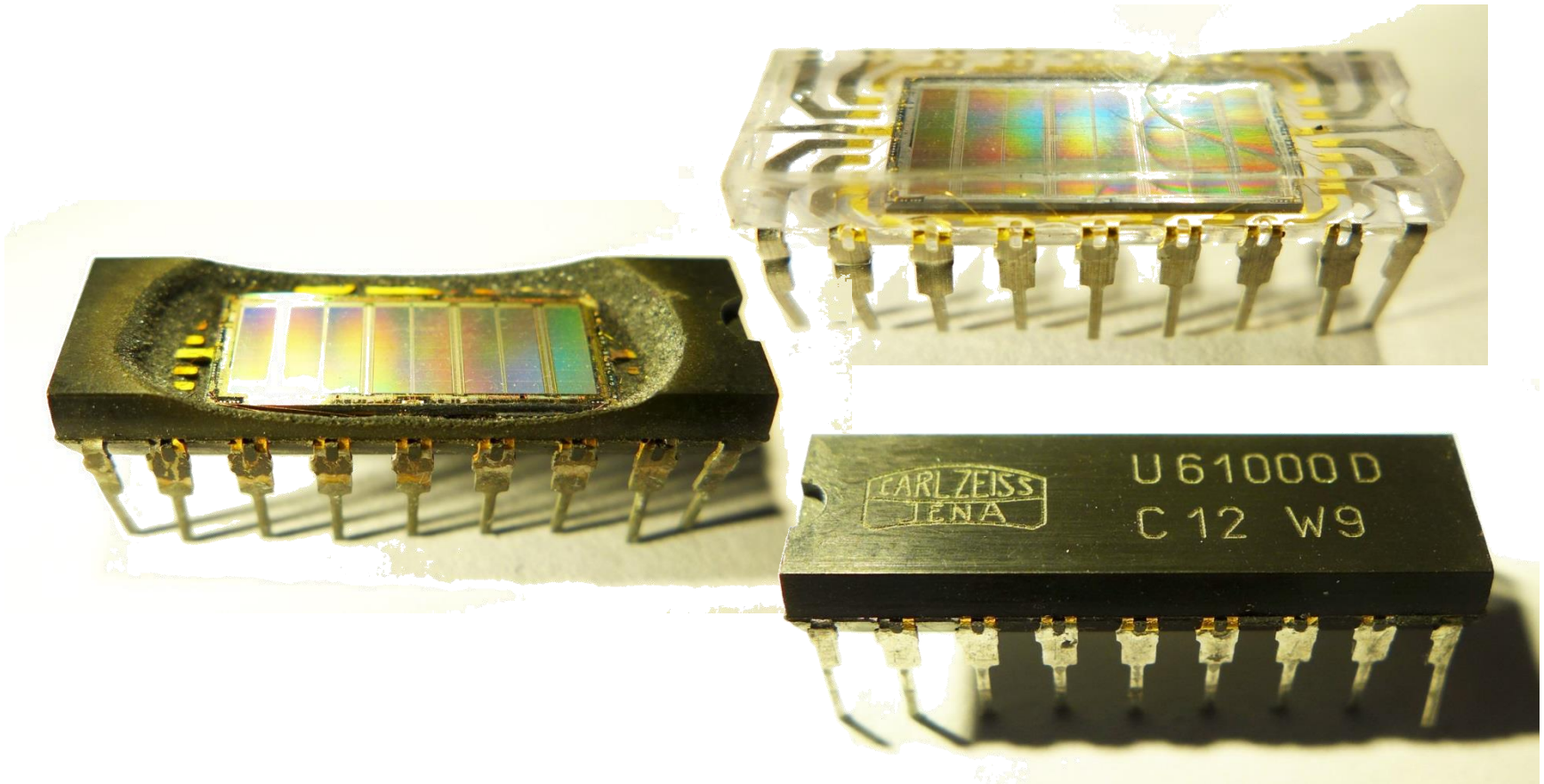
□ Fremdmuster

ZMD



1 M Speicher

- Eigene Lösung DIL-Plast



1 M Speicher

□ DIP MK 18

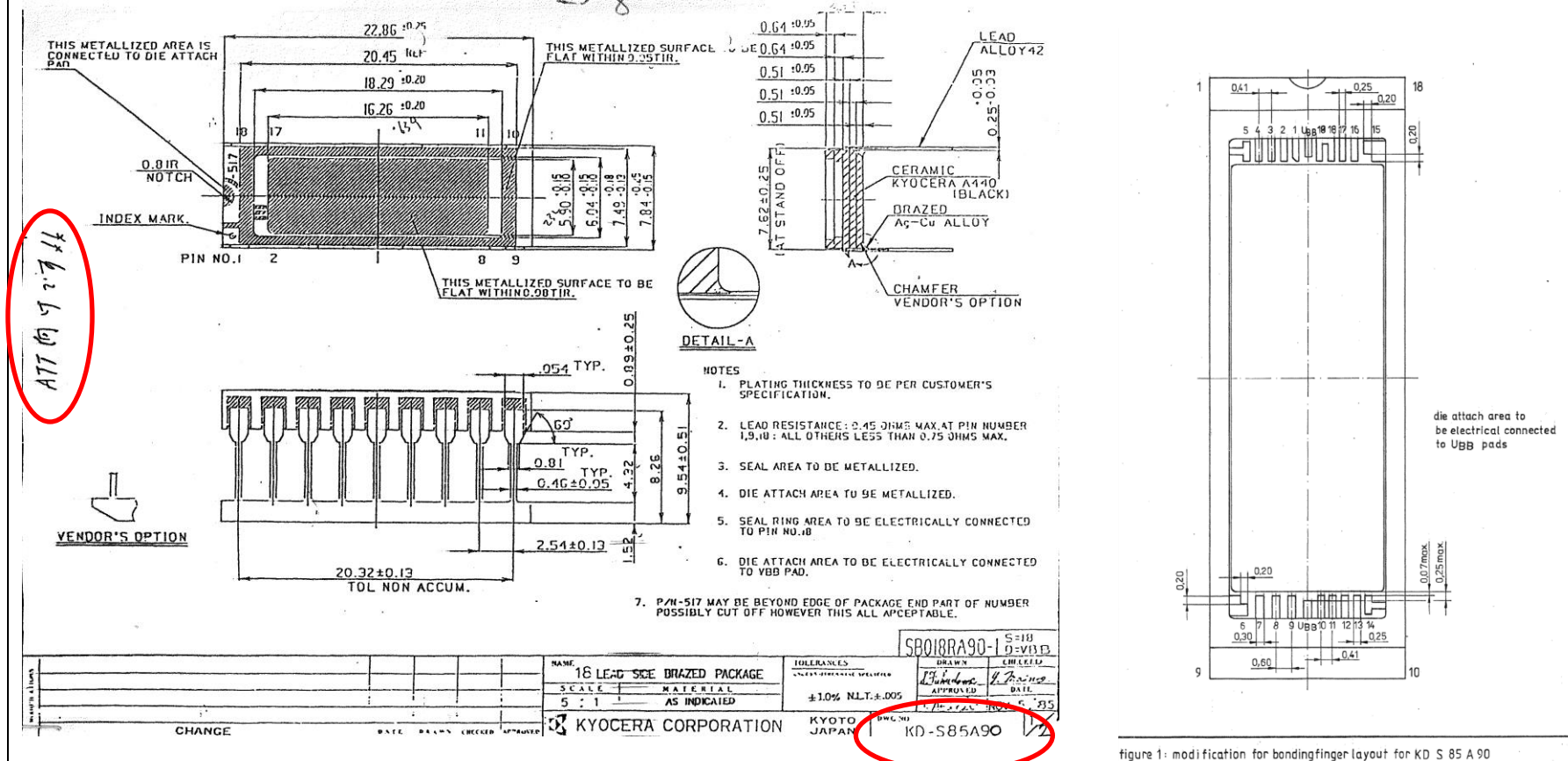
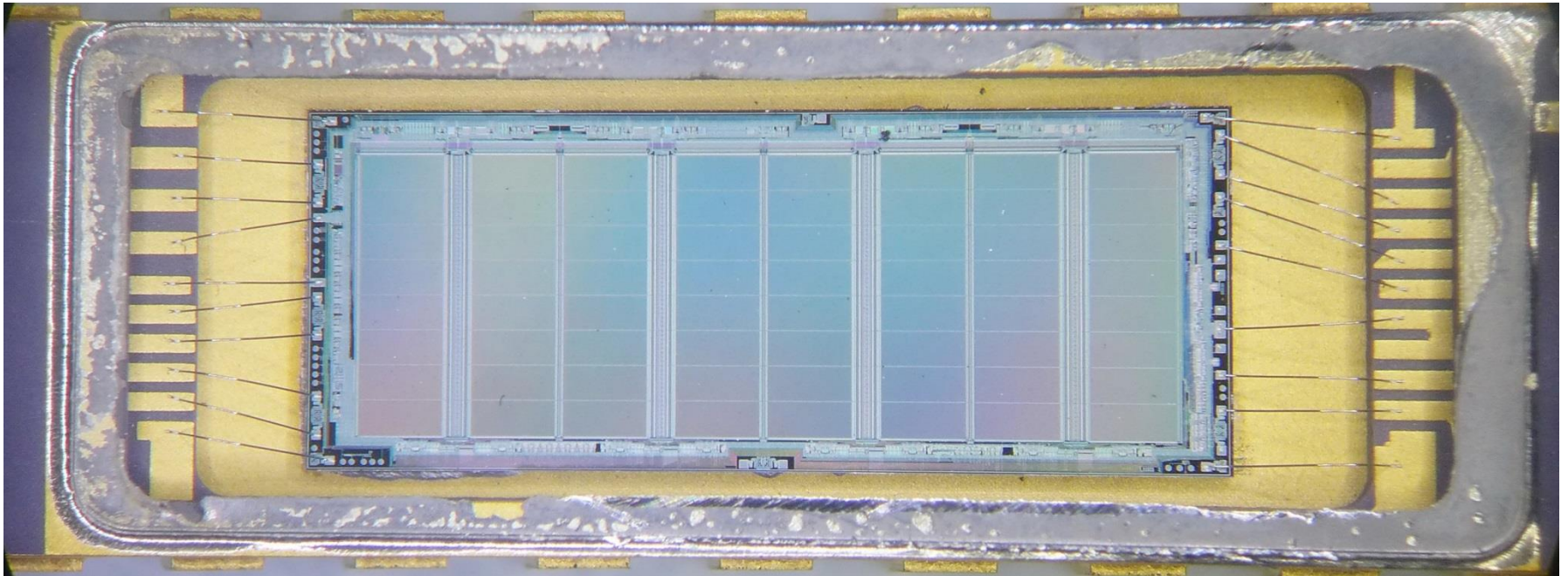


figure 1: modification for bonding finger layout for KD S 85 A 90














1 M Speicher

- Eigene Lösung DIK MK 18



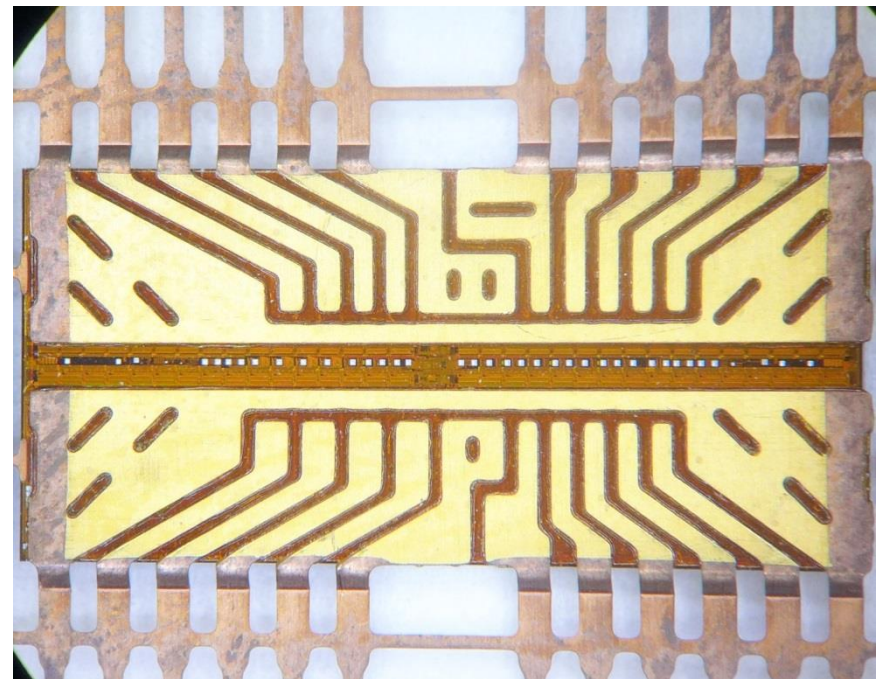
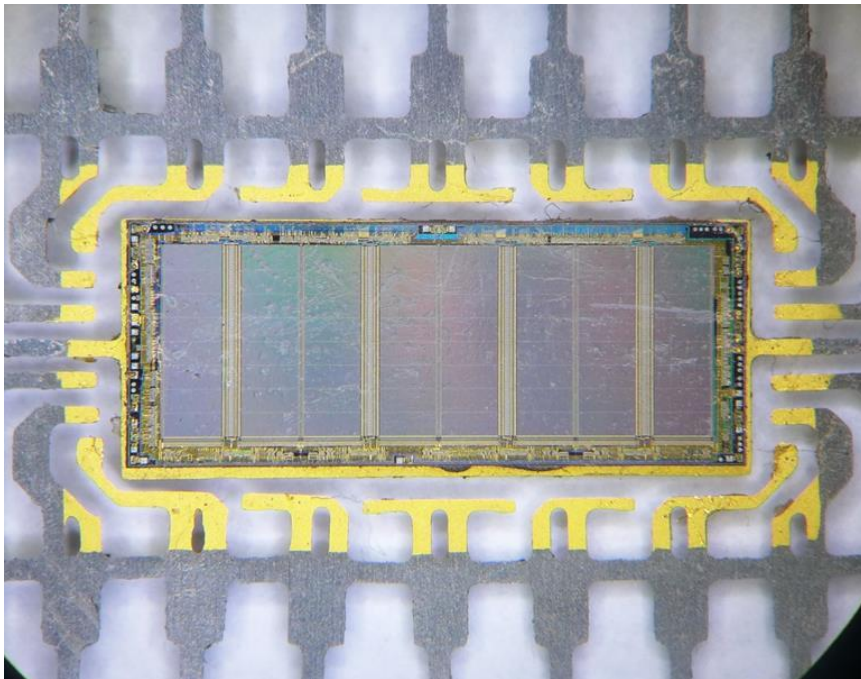
Packageentwicklung Speicher

- Packageentwicklung
 - Bauform / Montagetechnologie / Padlayout

Bauform	DIP / SO	SO / TSOP	TSOP / FBGA	FBGA	FBGA
					
Montagetechnologie	TS-Standard	LOC BOC	LOC BOC	COB über RDL stacked	TSV stacked
Padlayout					
Chipdicke	350 μm	250 μm	200 μm		100 μm
Speicherkapazität	256 k/ 1M	16 M	1 G	> 1 G	> 4 G
					

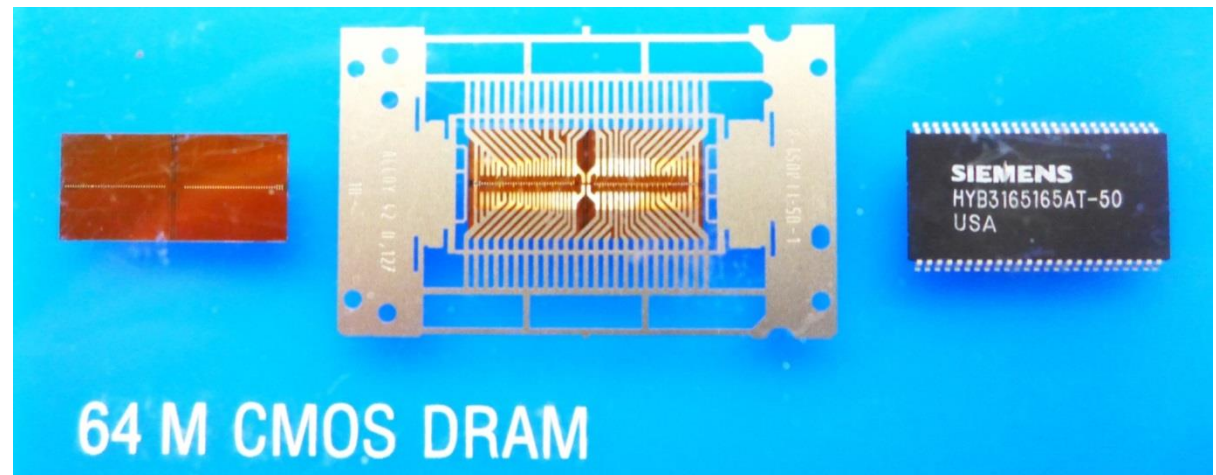
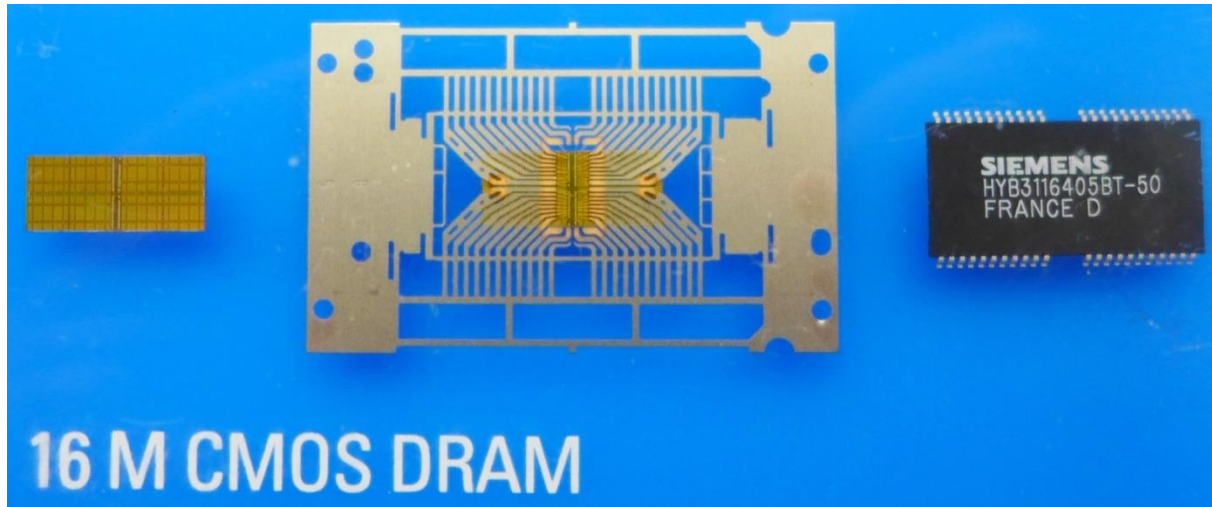
Packageentwicklung Speicher

- Packageentwicklung DIP auf LOC



Packageentwicklung Speicher

□ Packageentwicklung LOC



Quelle Siemens



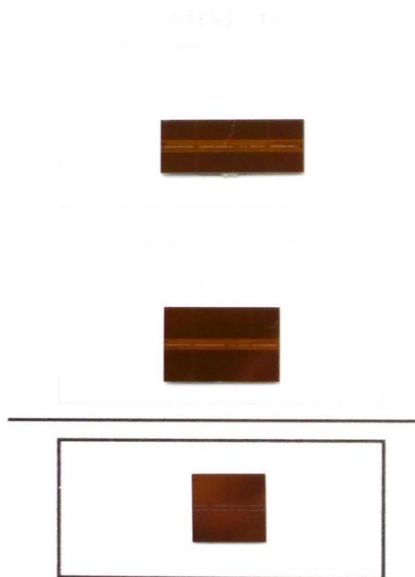
Packageentwicklung Speicher

□ Packageentwicklung BOC - FBGA

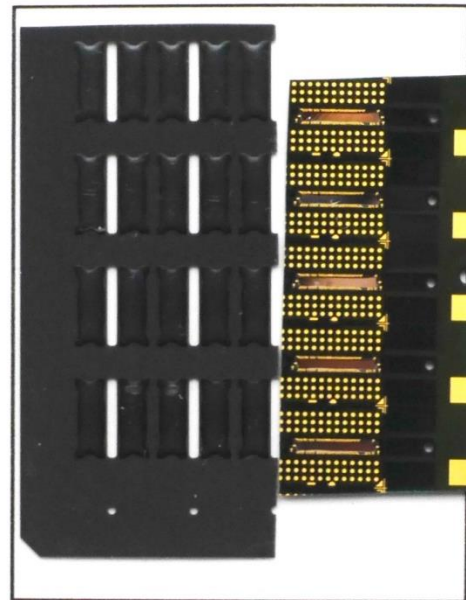


Last QD Backend Product

PG-TFBGA-78-151
PG-TFBGA-96-151

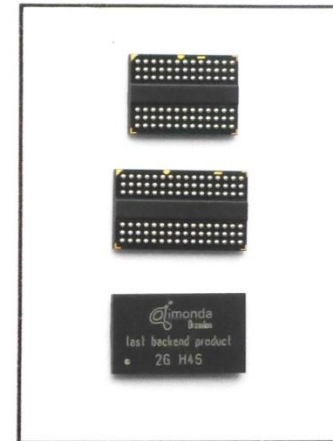


46 nm bWLTechology
52.98 mm² Chip Area
(7,55 x 7,01) mm³



1L-BOC Substrate
Wedge Pad Pitch = 150 µm
Min Trace Width = 20 µm

2G DDR3-SDRAM
H46
Substrate Step4



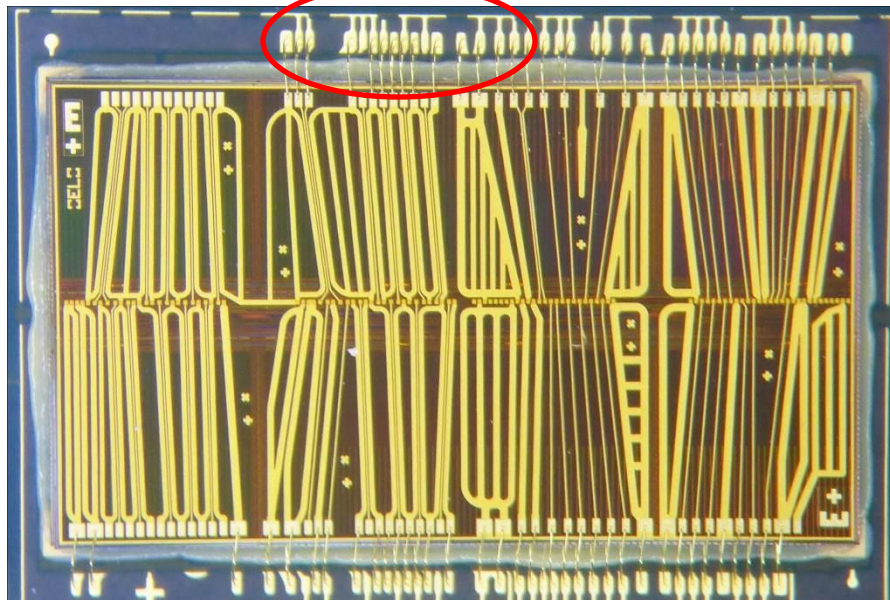
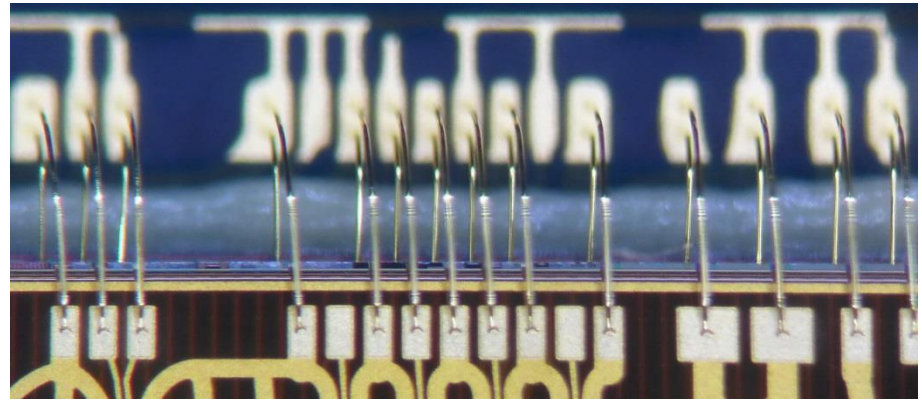
(8 x 13,5 x 1.2) mm³
(8 x 11 x 1.2) mm³
Ball Diameter 450 µm
Pitch (0.8 x 0.8) mm²

Quelle Qimonda



Packageentwicklung Speicher

- Packageentwicklung COB
 - Chip mit Umverdrahtung (RDL)
 - 2-fach Stapel



Quelle Qimonda

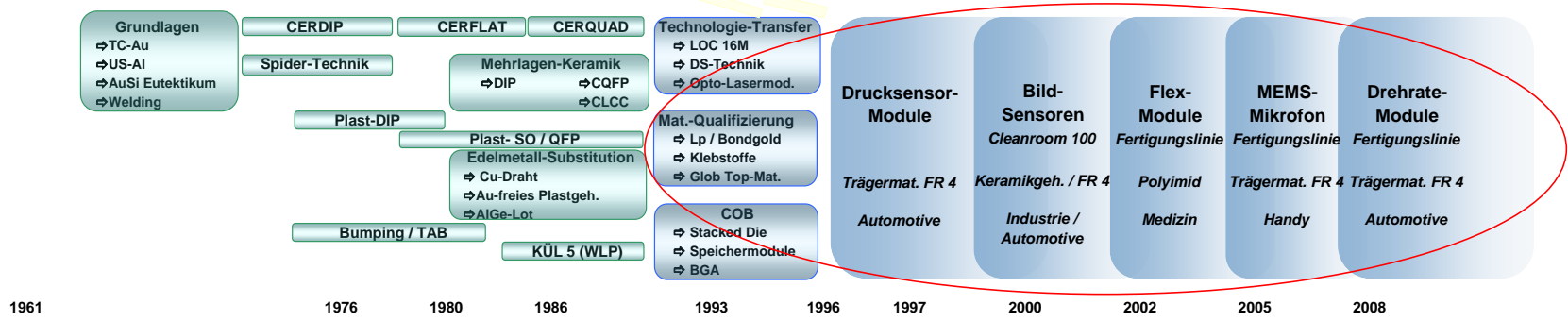
Alternativen zum Standard Package

⇒ COB tauglich für Massenverfahren

- Anforderungen / Systemuntersuchungen
 - Leiterplatten (PCB) Aufbau u. Materialien
 - Metallisierung (Bondgold)
 - Klebstoffe
 - Abdeckmaterialien (GlobTop)

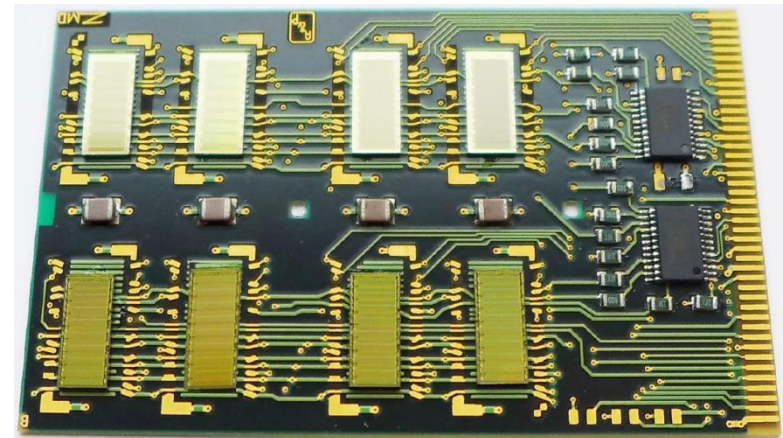
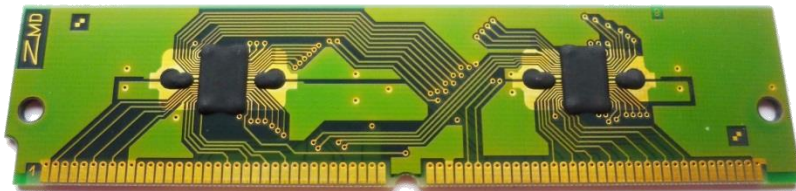
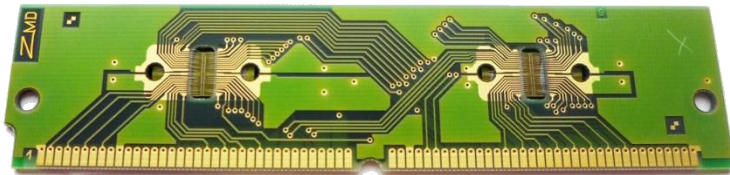
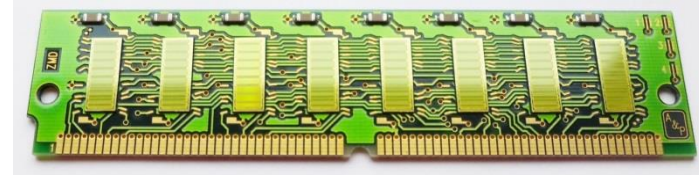
Alternativen zum Standard Package

COB / Modultechnik



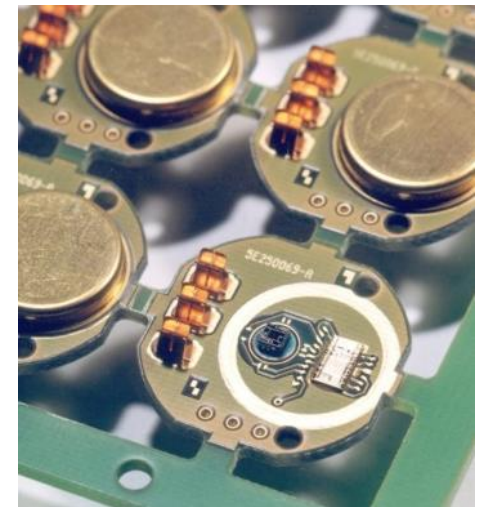
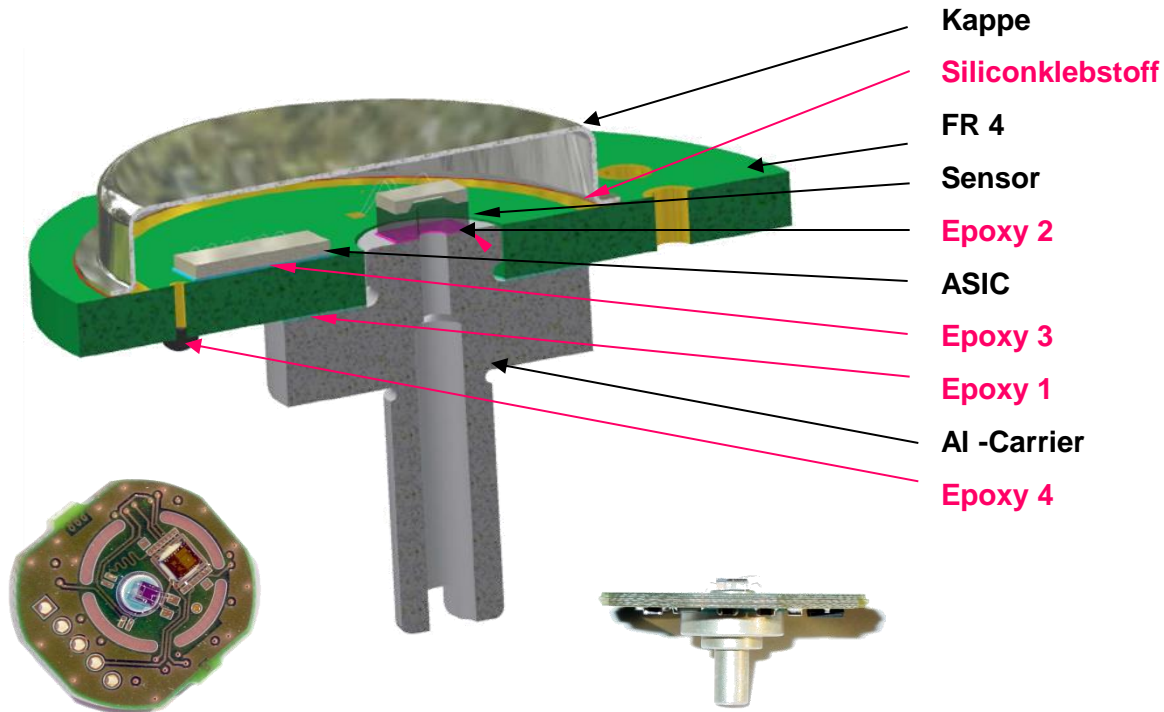
Alternativen zum Standard Package

□ Speichermodule



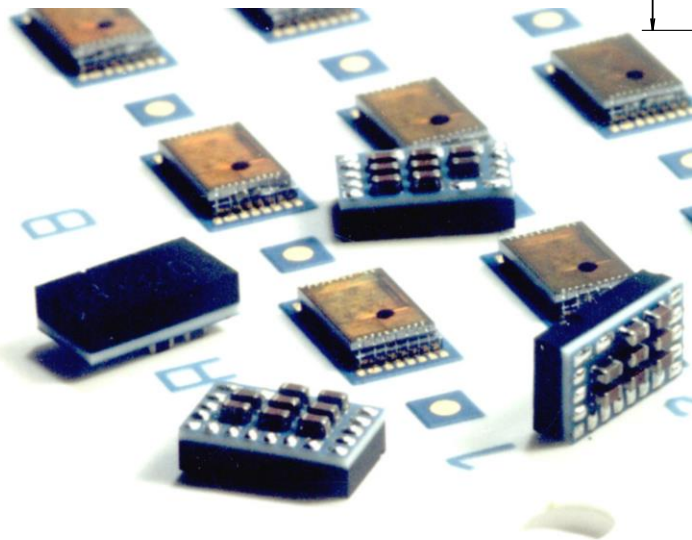
Alternativen zum Standard Package

□ Drucksensormodul

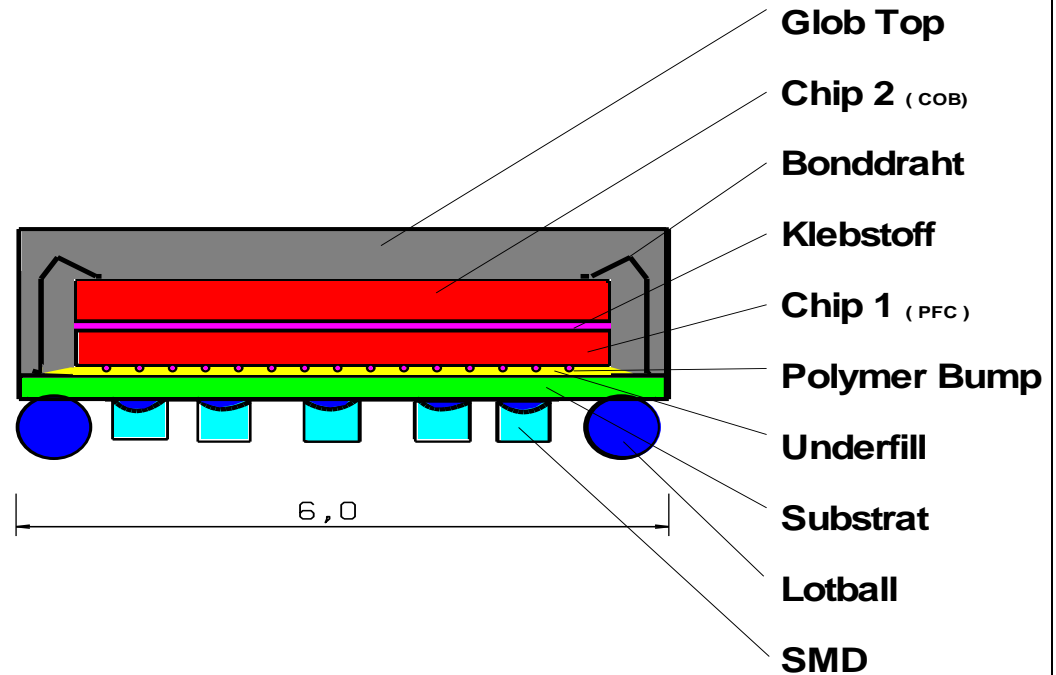


Alternativen zum Standard Package

3D –Chip Modul

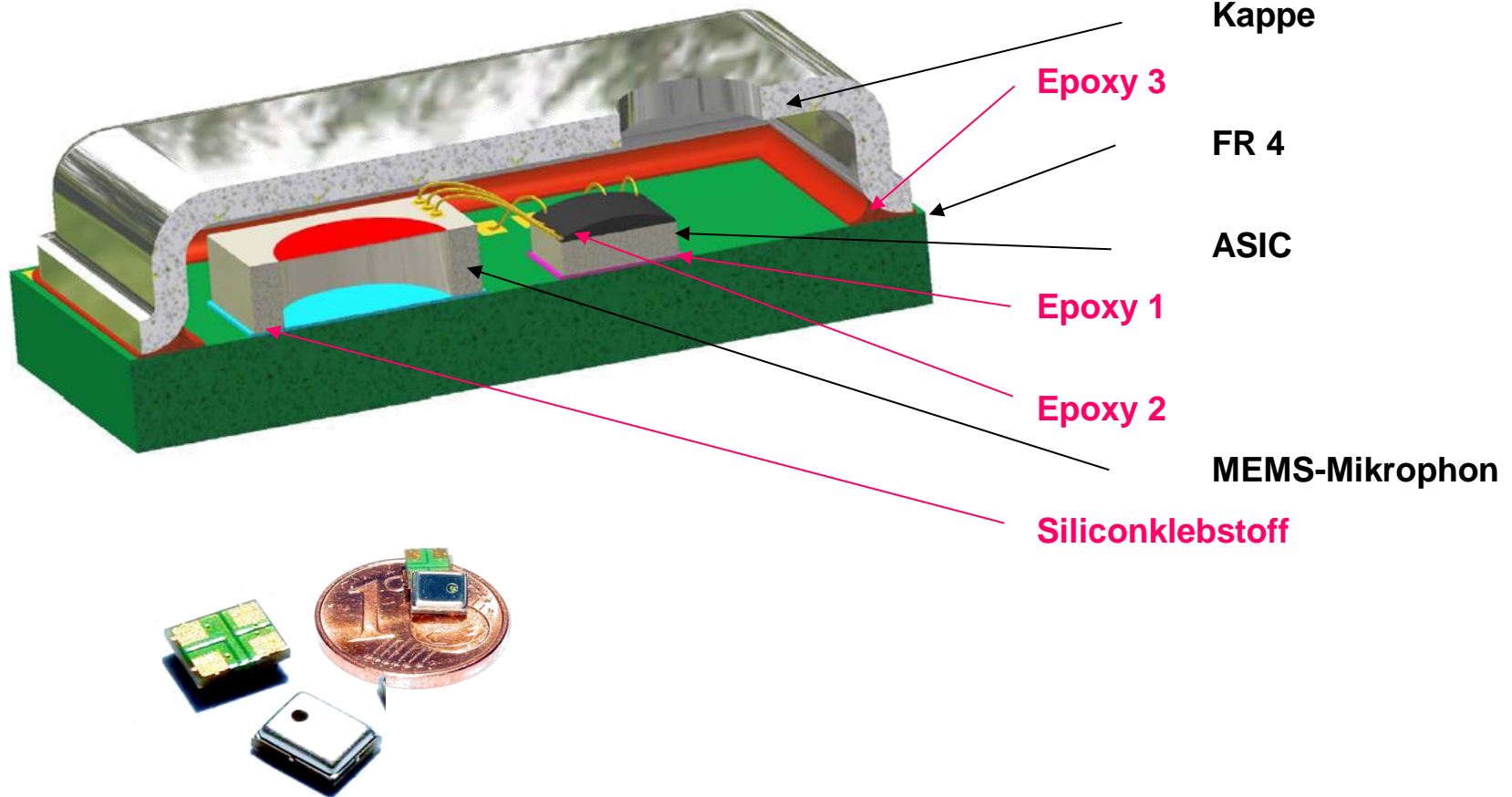


max. 2,5



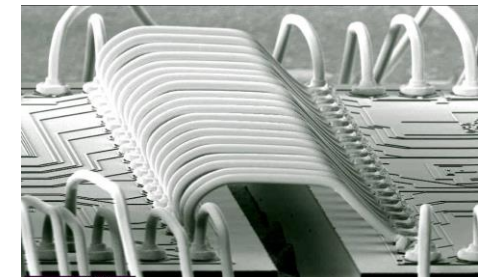
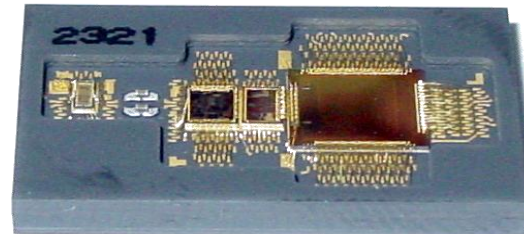
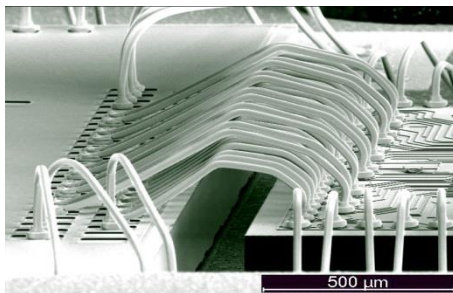
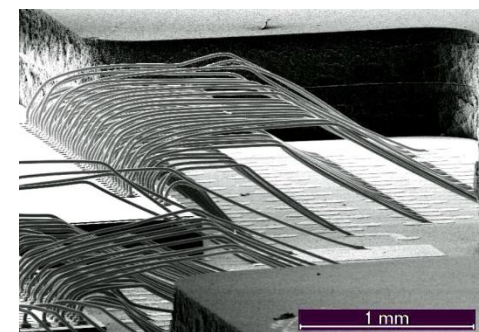
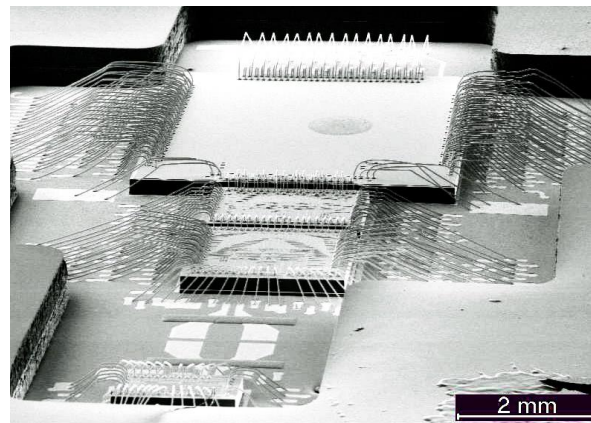
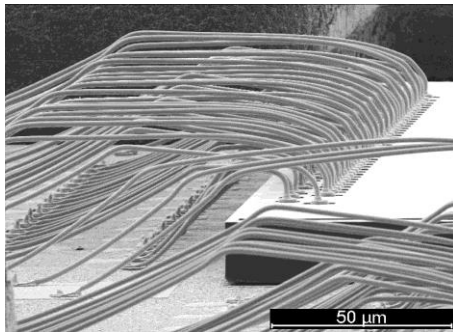
Alternativen zum Standard Package

MEMS Mikrofon



Alternativen zum Standard Package

□ MCM Module

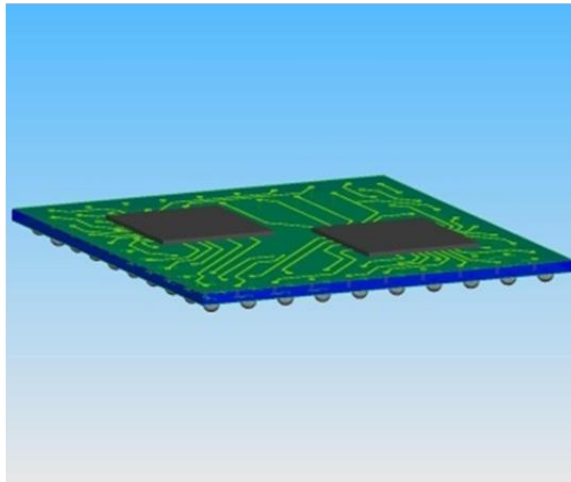


Merkmale: Body: 12 x 21 mm²
Layer: 13 AlN
PV_{max.}: 20 W

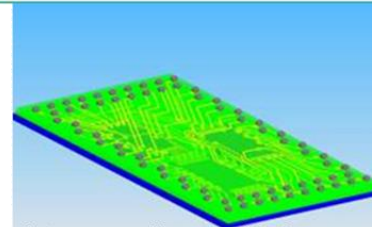
Drahtdurchmesser: Au 30 μm
Anzahl Drahtbonds: 500
Bondpitch: 50 μm, staggered

Alternativen zum Standard Package

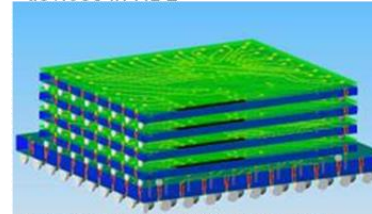
- Systemintegration
 - 3D System Architectures –TSV-Interposer



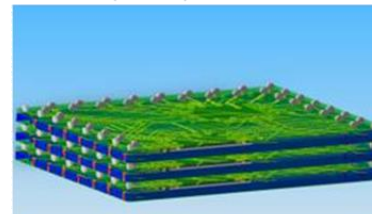
Silicon interposer as device carrier between devices and package / board for high IO count and high interconnect density (multi-layer, 5-10 μm line/space)



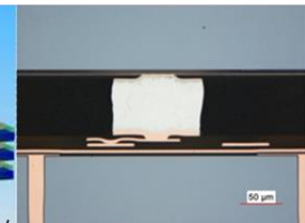
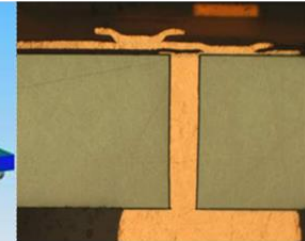
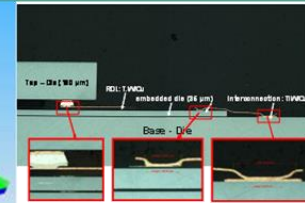
Interposer with embedded devices in RDL



Interposer with TSV & stacked devices (w TSV)



Stacked modular Interposer w. TSV



M.J. Wolf

Fraunhofer IZM



Alternativen zum Standard Package

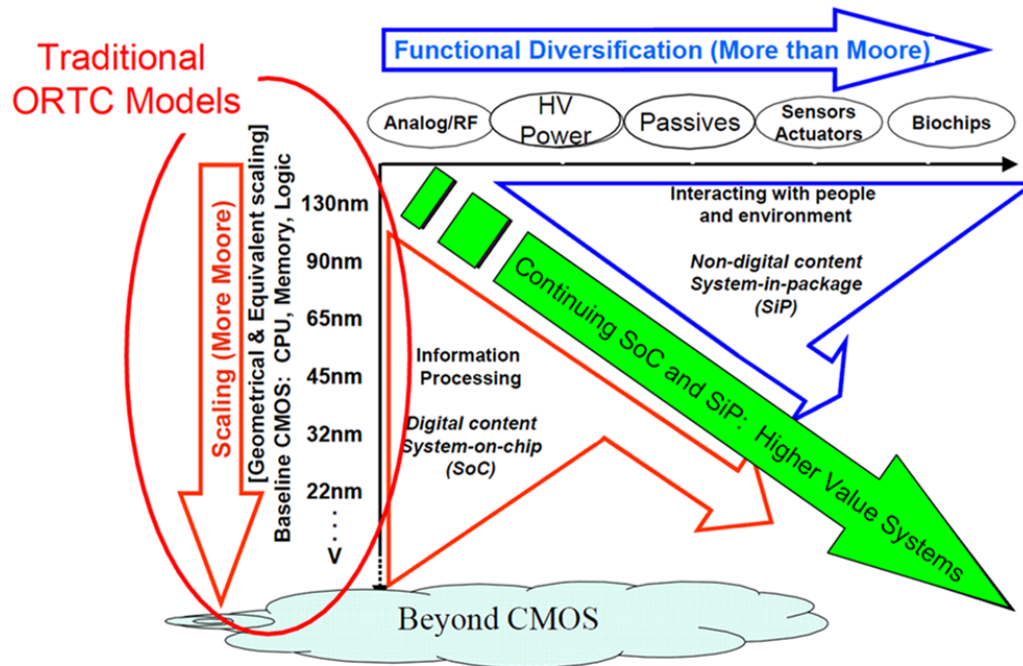
- Systemintegration
 - TSV - Prozess



Alternativen zum Standard Package

- Systemintegration

Motivation for 3D Heterogeneous Integration - SiP



M.J. Wolf

Fraunhofer
IZM

